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Designated/Elected Office (DO/EO/US)

10/523371

DT05 Rec'd PCT/PTO 02 FEB 2005

U.S. National Stage of
International Application No.: PCT/US2004/017251

International Filing Date: 01 June 2004

Earliest Priority Date: 02 June 2003

Applicants: Jeffrey J. Spiegelman, Daniel Alvarez, Jr., Russell J. Holmes,
and Allan Tram

Title: METHOD FOR THE REMOVAL OF AIRBORNE MOLECULAR
CONTAMINANTS USING OXYGEN AND/OR WATER GAS MIXTURES

Date: 2 February 2005

EXPRESS MAIL LABEL NO. EV 214960082 US

INFORMATION DISCLOSURE STATEMENT

Mail Stop PCT
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

This Information Disclosure Statement is submitted:

under 37 CFR 1.129(a), or
(First/Second submission after Final Rejection)

under 37 CFR 1.97(b), or

(Within any one of the following time periods: three months of filing national application (other than a CPA) or date of entry of the national stage in an international application; or before the mailing date of a first office action on the merits in a non-provisional application, including a CPA, or a Request for Continued Examination).

under 37 CFR 1.97(c) together with either:

a Statement under 37 CFR 1.97(e), as checked below, or

a \$180.00 fee under 37 CFR 1.17(p), or

(After the 37 CFR 1.97(b) time period, but before final action or notice of allowance, whichever occurs first)

under 37 CFR 1.97(d) together with:

a Statement under 37 CFR 1.97(e), as checked below, and

a \$180.00 fee under 37 CFR 1.17(p), or

(Filed after final action or notice of allowance, whichever occurs first, but on or before payment of the issue fee)

under 37 CFR 1.97(i):

Applicant requests that the IDS and cited reference(s) be placed in the application filewrapper.

(Filed after payment of issue fee)

Statement Under 37 CFR 1.97(e)

- Each item of information contained in this Information Disclosure Statement was first cited in any communication from a foreign patent office in a counterpart foreign application not more than three months prior to the filing of this Information Disclosure Statement; or
- No item of information contained in this Information Disclosure Statement was cited in a communication from a foreign patent office in a counterpart foreign application, and, to the knowledge of the undersigned, after making reasonable inquiry, no item of information contained in the information disclosure statement was known to any individual designated in 37 CFR 1.56(c) more than three months prior to the filing of this Information Disclosure Statement.

Statement Under 37 CFR 1.704(d) (Patent Term Adjustment)

Applies to original applications (other than design) filed on or after May 29, 2000

- Each item of information contained in the Information Disclosure Statement was cited in a communication from a foreign patent office in a counterpart application and this communication was not received by any individual designated in § 1.56(c) more than thirty days prior to the filing of the Information Disclosure Statement.

Enclosed herewith is form PTO-1449:

Copies of the cited references are enclosed.

Copies of issued U.S. patents and published U.S. applications are not required and are not being provided.

Copies of the cited references are enclosed except those entered in prior application, U.S. Application No. [], to which priority under 35 U.S.C. 120 is claimed. [The earlier application contains copies of the cited references.]

The listed references were cited in the enclosed International Search Report in a counterpart foreign application.

The "concise explanation" requirement (non-English references) for reference AN under 37 CFR 1.98(a)(3) is satisfied by:

the explanation provided on the attached sheet.

the explanation provided in the Specification.

submission of the enclosed International Search Report.

submission of the enclosed English-language version of a foreign Search Report and/or foreign Office Action.

the enclosed English language abstract.

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[] Applicant requests that the following non-published pending applications be considered:

Examiner's
Initials

____ U.S. Patent Application No. [], by [inventor(s)], filed [], Docket No.: []

____ U.S. Patent Application No. [], by [inventor(s)], filed [], Docket No.: []

____ U.S. Patent Application No. [], by [inventor(s)], filed [], Docket No.: []

____ Examiner

____ Date

[] A copy of each above-cited application, including the current claims, is enclosed, except any application filed on or after June 30, 2003, which has been scanned into the PTO's Image File Wrapper (IFW) system and is available to the examiner.

[] A copy of each above-cited application, including the current claims, is enclosed, except those entered in prior application, U.S. Application No. [], to which priority under 35 U.S.C. 120 is claimed.

The Examiner is requested to return a copy of the above list of pending applications indicating which references were considered with the next office communication.

It is requested that the information disclosed herein be made of record in this application.

Method of payment:

[] A check for the fee noted above is enclosed, or the fee has been included in the check with the accompanying Reply. A copy of this Statement is enclosed.

[] Please charge Deposit Account 08-0380 in the amount of \$[]. A copy of this Statement is enclosed.

[X] Please charge any deficiency in fees and credit any overpayment to Deposit Account 08-0380.

Respectfully submitted,

HAMILTON, BROOK, SMITH & REYNOLDS, P.C.

By



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Concord, MA 01742-9133

Dated: 2 Feb. 2005

3194.1026-006

INFORMATION DISCLOSURE STATEMENT IN AN APPLICATION

February 1, 2005

(Use several sheets if necessary)

FIRST NAMED INVENTOR
Jeffrey J. Spiegelman

EXAMINER

1 FILING DATE

10/523371

FILING DATE

CONFIRMATION NO.

GROUP

U.S. PATENT DOCUMENTS

EXAMINER	DATE CONSIDERED
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PTO-1449 REPRODUCED	ATTORNEY DOCKET NO. 3194.1026-006	APPLICATION NO. 10/523371
INFORMATION DISCLOSURE STATEMENT IN AN APPLICATION	FIRST NAMED INVENTOR Jeffrey J. Spiegelman	FILING DATE
February 1, 2005 (Use several sheets if necessary)	EXAMINER	CONFIRMATION NO.
		GROUP

EXAMINER	DATE CONSIDERED
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PTO-1449 REPRODUCED		ATTORNEY DOCKET NO. 3194.1026-006	APPLICATION NO. 10/523371
INFORMATION DISCLOSURE STATEMENT IN AN APPLICATION		FIRST NAMED INVENTOR Jeffrey J. Spiegelman	FILING DATE
February 1, 2005 (Use several sheets if necessary)		EXAMINER	CONFIRMATION NO.
			GROUP

FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER Country Code-Number-Kind Code (if known)	DATE MM-DD-YYYY	NAME OF PATENTEE OR APPLICANT OF CITED DOCUMENT	TRANSLATION YES NO
	AL	WO 01/37329 A1	05-25-2001	Lucent Technologies, Inc.	
	AM	EP 0 867 924 A2	09-30-1998	Interuniversitair Micro-Elektronica Centrum VZW 3001 Heverlee (BE)	
	AN	DE 199 24 058 A1 (appended English <i>Abstract</i> Translation)	11-30-2000	Robert Bosch GmbH	
	AO				
	AP				
	AQ				
	AL2				
	AM2				
	AN2				
	AO2				
	AP2				
	AQ2				
	AL3				
	AM3				
	AN3				
	AO3				
	AP3				
	AQ3				
	AL4				
	AQ4				

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PTO-1449 REPRODUCED

INFORMATION DISCLOSURE STATEMENT
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ATTORNEY DOCKET NO.
3194.1026-006

APPLICATION NO.

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FIRST NAMED INVENTOR
Jeffrey J. Spiegelman

FILING DATE

EXAMINER

CONFIRMATION NO.

GROUP

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

	AR	Handbook of Semiconductor Wafer Cleaning Technology, Science, Technology, and Applications, Werner Kern Associates, eds., (NJ: Noyes Publications) pp. 88-89 (1993).
	AS	Veillerot, Marc, "A Method for Measuring AMC Concentrations Inside Wafer Containers," Materials Integrity Management Symposium 2003.
	AT	Martin, Ray <i>et al.</i> , "Status of Microenvironment Gas Purge in the Semiconductor Industry," Materials Integrity Management Symposium 2003.
	AU	Davidson, John, "The Expanding Role of Bare Reticle Stockers in Photolithography," Materials Integrity Management Symposium 2003.
	AV	Veillerot <i>et al.</i> , "Organic Contamination: Purge Gas Impace in Plastic Storage Boxes," Solid State Phenomena, vol. 92, pp. 105-108 (2003).
	AW	Veillerot <i>et al.</i> , "Testing the use of purge gas in wafer storage and transport containers," [online] 1997-2003 [retrieved 2004-11-10]. Retrieved from the Internet <URL: http://www.micromagazine.com/archive/03/08/verllerot.html
	AX	Pearlstein <i>et al.</i> , "Evaluating electronics-grade gas-line purging requirements," [online] March, 2001 [retrieved 2004-10-18]. Retrieved from the Internet <URL: http://sst.pennnet.com/Articles/Article_Display.cfm?Section=ARCHI&ARTICLE_ID=95491&VERSION_NUM=1&p=5
	AY	
	AZ	
	AR2	
	AS2	
	AT2	

EXAMINER

DATE CONSIDERED